

**STATEMENT OF INTENT  
BETWEEN  
THE NATIONAL INSTITUTE OF STANDARDS AND TECHNOLOGY  
OF THE DEPARTMENT OF COMMERCE  
OF THE UNITED STATES OF AMERICA  
AND  
THE KOREAN AGENCY FOR TECHNOLOGY AND STANDARDS  
OF THE MINISTRY OF COMMERCE, INDUSTRY AND ENERGY  
OF THE REPUBLIC OF KOREA**

Whereas the National Institute of Standards and Technology of the Department of Commerce of the United States of America, and the Korean Agency for Technology and Standards of the Ministry of Commerce, Industry and Energy of the Republic of Korea, hereinafter referred to as "the Parties," continue to support cooperation in the field of standardization, conformity assessment and legal metrology on the basis of equality and mutual benefit;

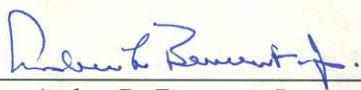
Whereas the Parties recognize that such cooperation promotes economic cooperation and supports the friendly relationship between the United States of America and the Republic of Korea; and

Whereas the Parties are pleased with the on-going cooperation, and particularly with the establishment of a new Project Annex on the Development of Nano-Bio Reference Materials and Measurements using Fluorescence Semiconductor Nanocrystals.

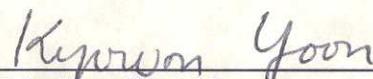
Now therefore, the National Institute of Standards and Technology of the United States Department of Commerce, and the Korean Agency for Technology and Standards of the Ministry of Commerce, Industry and Energy jointly declare their intent to continue this mutually beneficial cooperation and to explore opportunities for expanded cooperation.

In Witness Whereof, signed this 16<sup>th</sup> day of July, 2004

FOR THE NATIONAL INSTITUTE OF  
STANDARDS AND TECHNOLOGY OF  
THE DEPARTMENT OF COMMERCE OF  
THE UNITED STATES OF AMERICA

By   
Name: Arden L. Bement, Jr.  
Title: Director, National Institute of  
Standards and Technology

FOR THE KOREAN AGENCY FOR  
TECHNOLOGY AND STANDARDS  
OF THE MINISTRY OF COMMERCE,  
INDUSTRY AND ENERGY  
OF THE REPUBLIC OF KOREA

By   
Name: Mr. Kyo-Won Yoon  
Title: Administrator, Korean Agency for  
Technology and Standards